ABSTRACT

TITLE:

Injection system for an apparatus for depositing thin layers by vacuum evaporation

APPLICANT:

RIBER

The invention concerns an injection system for an apparatus for depositing thin layers by vacuum evaporation, said injection system comprising a container (4) for receiving a material to be evaporated, container heating means adapted to evaporate said material, at least one injection ramp (1) comprising an inner conduit connected to the container so as to receive said evaporated material and a plurality of nozzles (3), each nozzle comprising at least a communication channel so as to diffuse the evaporated material into said vacuum evaporation chamber. According to the invention, the injection ramp (1) comprises a plurality of injection modules (2a, 2b, 2c, 2d, 2e) mechanically connected to each other in series along a longitudinal direction (5), each injection module comprising a plurality of injection nozzles, and said injection ramp comprises means of adjusting the orientation of said injection modules about said longitudinal direction so as to align said injection nozzles along a line parallel to said longitudinal direction (5).

Figure 1